

APPLICATION DATA SHEET

Electronic Version 0.0.11

Stylesheet Version: 1.0

Attorney Docket Number: 740756-2680

Publication Filing Type: new-utility

Application Type: utility

Title of Invention: PLASMA TREATMENT APPARATUS AND METHOD FOR PLASMA TREATMENT

Legal Representative:

Attorney or Agent: Jeffrey L. Costellia

Registration Number: 35483

Customer Number Correspondence Address: 22204

22204

Foreign Priority:

2002-358782

JP 2002-12-10

Priority Claimed

Assignee (Publish): Semiconductor Energy Laboratory Co., Ltd.

398, Hase,

Atsugi-shi, 243-0036 Kanagawa-ken JP

INVENTOR(s):

Primary Citizenship: JAPAN

Given Name: Shunpei

Family Name: YAMAZAKI

Residence City: Setagaya, Tokyo

Residence Country: JP

Address: c/o Semiconductor Energy Laboratory Co., Ltd.

398, Hase,

Atsugi-shi, Kanagawa-ken, 243-0036 JP

Primary Citizenship: JAPAN

Given Name: Yasuyuki

Family Name: ARAI

Residence City: Atsugi, Kanagawa
Residence Country: JP
Address: c/o Semiconductor Energy Laboratory Co., Ltd.
398, Hase,
Atsugi-shi, Kanagawa-ken, 243-0036 JP

Primary Citizenship: JAPAN
Given Name: Yasuko
Family Name: WATANABE
Residence City: Atsugi, Kanagawa
Residence Country: JP
Address: c/o Semiconductor Energy Laboratory Co., Ltd.
398, Hase,
Atsugi-shi, Kanagawa-ken, 243-0036 JP